

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
Kiyofumi SAKAGUCHI, et al.) : Examiner: George R. Fourson, III
Application No.: 09/161,774) : Group Art Unit: 2823
Filed: September 29, 1998) : Confirmation No.: 8032
For: PROCESS FOR PRODUCTION OF) : September 8, 2006
SEMICONDUCTOR SUBSTRATE :
;

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

SIXTH INFORMATION DISCLOSURE STATEMENT

Sir:

In compliance with the duty of disclosure under 37 C.F.R. § 1.56 and in accordance with the practice under 37 C.F.R. §§ 1.97 and 1.98, the Examiner's attention is directed to the documents listed on the enclosed Form PTO-1449. Copies of the listed documents, other than U.S. patent documents, are enclosed.

REMARKS

An English-language Abstract for JP-A 60-196955 was obtained from a commercial database and is also enclosed.

FORMAL MATTERS

No fee is believed due; however, any fee required in connection with this paper should be charged to Deposit Account No. 06-1205.

CONCLUSION

It is respectfully requested that the above information be considered by the Examiner and that a copy of the enclosed Form PTO-1449 be returned indicating that such information has been considered.

Applicant's undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should continue to be directed to our address given below.

Respectfully submitted,

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Attorney for Applicant
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FORM PTO 1449 (<i>modified</i>) U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary)			ATTY DOCKET NO. 03500.010530.4 (35.C10530 C1/D2)		APPLICATION NO. 09/161,774		
			APPLICANT Kiyofumi SAKAGUCHI, et al.				
			FILING DATE September 29, 1998		GROUP 2823		
Dated Submitted to USPTO: September 8, 2006							
U.S. PATENT DOCUMENTS							
*EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
		5,175,610	12/29/1992	Kobayashi	257	676	
		4,670,763	06/02/1987	Ovshinsky, et al.	357	4	
		4,555,586	11/26/1985	Guha, et al.	136	259	
		4,426,657	01/17/1984	Abiru, et al.	357	29	
		4,064,521	12/20/1977	Carlson	357	2	
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT
		60-196955	10/05/1985	Japan			Abstract
		0 469 630 A2	02/05/1992	Europe			
OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)							
		T. Yasumatsu, et al., "Ultrathin Si Films Grown Epitaxially on Porous Silicon", Applied Surface Science, Vols. 48 & 49, pp. 414-418 (1991)					
		Handbook of Thin Film Technology, 5-17 to 5-25 (Eds., L. I. Maissel and R. Glang 1970)					
		Robert F. Pierret, <u>Semiconductor Device Fundamentals</u>, pp. 347-368					
EXAMINER				DATE CONSIDERED			

***EXAMINER:** Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)							
		S.M. Sze, Physics of Semiconductor Devices, pp. 63-128, 847-849, 2nd Edition (1981)					
		W. Kern & V. Ban, <u>Thin Film Processes</u>, Chemical Vapor Deposition of Inorganic Thin Films, pp. 257-331 (1978)					
		W. Luft & Y. Tsuo, <u>Hydrogenated Amorphous Silicon Alloy Deposition Processes</u>, pp. 125-144 (1993)					
		R. Pierret, Modular Series on Solid State Devices, Vol. 4, pp. 59-80 (1983)					
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Sheet 2 of 2

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